



- Experimental setup
- Be plasma concentrations
- Fluence dependence of chemical erosion
- Influence of Be seeding on chemical erosion
- Temperature dependence of Be sputtering
- Summary and Outlook



Experimental setup









Sample change



Decontamination





Be plasma concentrations





- For $T_e >= 6 \text{ eV}$ all Be is ionized, (as expected from ionization length of ~ 1 cm @ Te = 6eV)
- Be concentration up to several percent possible (green plasma incident)





SEM image <u>before</u> exposure

- Polished, pyrolythic graphite samples
- Only detectable (EDX) impurity O
- Samples are cut parallel to graphite planes
- Degassed at 1000°C for 20 min







Fluence dependence of chemical erosion Experiment I





• Exp. fit indicates e-folding time of ~ 3000 s

SEM image of sample after exposure



• Formation of "grass" like structures

• EDX/XPS/AES Show no Mo, Be, B on surface





Fluence dependence of chemical erosion



Experiment II



SEM image after exposure



Sample surface is recessed





• No change (measurable) in CD-band at low temperatures

SEM image after exposure



• "Grass" starts to evolve but does not reach the height as for high temperatures





Influence of Be seeding on chemical erosion Fluence dependence & Be seeding



Normalized, background subtracted CD intensity



- 40% drop without Be in CD band
- 60% drop with Be in CD band
- Final Be surface concentration: 15 % (AES)

SEM image after exposure (330° C sample temp., Be seeding)



- Surface is covered with "tree trunks"
- Top of trunks contain Mo & Be



- Clear dependence of CD-band intensity on Be oven temperature / Be plasma concentration
- Increased Be sputtering at 50 V bias reduces Be sample concentration

yields less reduction in chemical erosion



Influence of Be seeding on chemical erosion



Be surfaces vs. Plasma concentration Simulated Be surface concentration in equilibrium





• Despite the observed morphology changes, simulation still gives correct order of magnitude

• Plasma concentrations ~ 2% should result in a fully Be covered surface











Catcher probe manipulator





- Manipulator has been manufactured at IPP and delivered to UCSD
- Will be installed and tested in January

Sample

Beam dump

Sample lock







• CD band intensity / chemical erosion drops with fluence, probably due to changes in the surface morphology

• Be plasma seeding reduces CD band intensity / chemical erosion

- ? Chemical effect
- ? Surface coverage / shielding
- Yet to be determined

- ? Surface morphology
- Be surface concentration quickly increases with Be plasma concentration
- Be erosion exhibits a strong temperature dependence above 800 °C

 \rightarrow Most probably due to evaporation of weakly bonded surface atoms created by bombardment





Carbon/Beryllium:

- Repeat experiment with different type of carbon (POKO)
- Measure quantitatively the reduction of chemical erosion as function of Be plasma concentration
- Measure a possible reduction of physical sputtering
- Measure H retention as function of Be plasma concentration
- Influence of heavy impurities (Xe, Ne) on reduction of chemical erosion
- Investigate morphology changes during high fluence He bombardment
- Codeposition experiments with catcher probe

Experimental:

- Setup new spectroscopy system: Camera + ADC
- Install catcher probe

Simulation:

• Perform MD calculation of Be sputtering by D to explain temperature dependence